

INFORMATION DISCLOSURE CITATION  PTO-1449		ATTY. DOCKET NO. P132-US		SERIAL NO. Not Yet Assigned		
		APPLICANT Jim Dunphy, et al.				
		FILING DATE Herewith		GROUP Not Yet Assigned		
		<b>U.S. PATENT DOCUMENTS</b>				
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
Dle	U.S Pub App No. 2003/0002019	1/2/03	Miller			
	U.S Pub App No. 2002/0056898	5/16/02	Lopes, et al.			
	U.S Pub App No. 2002/0063322	5/30/02	Robbins, et al.			
	6,300,294	10/9/01	Robbins, et al.			
	5,694,740	12/9/97	Martin, et al.			
	5,936,758	8/10/99	Fisher, et al.			
Dle	5,610,438	3/11/97	Wallace, et al.			
Dle	5,512,374	4/30/96	Wallace, et al.			
<b>FOREIGN PATENT DOCUMENTS</b>						
EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION
						YES
						<input type="checkbox"/> <input type="checkbox"/>
<b>OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)</b>						
Dle	"Lubrication of Digital Micromirror Devices" Henck, Tribology Letters 3 (1997) 239-247					
	Micromotor Operation in a Liquid Environment" Dhuler, IEEE 1992 pgs 10-13					
	"Optimization of Lubricants for silica Micromotors" Zarrd, Sensors and Actuators A 46-47 (1995) 598-600					
	"Fabrication of packaged thin beam structures by an improved driving method" Masato Ohtsu, IEEE (1996) 0-7803-2985-6, pgs 228-233					
	"Operation of electrostatic micromotors in liquid environments" Mehran Mehregany, J. Micromech. Microeng. 2 (1992) 1-3					
	"Nanotribology and nanomechanics of MEMS devices", Nharad Bhushan, IEEE 0-7803-298-5-6, pgs 91-98					
	"Micromotor dynamics in lubricating fluids" Keren Deng, J. Micromech. Microeng. 4 (1994) 266-269					
	"Stiction reduction processes for surface micromachines" Roya Maboudian Tribology letters 3 (1997) 215-221					
	"Friction and Pull-off Force on Silicon Surface Modified by FIB" Ando IEEE 1996, 0-7803-2985-6/96, pgs 349-353					
	"Measurement of Micromotor Dynamics in Lubricating Fluids" Deng IEEE					
Dle	"Friction and Wear studies on Lubricants and materials Applicable to MEMS" Shigehisa Suzuki, IEEE 1991, pgs 143-147					
EXAMINER	Dle	DATE CONSIDERED				7/2005

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<b>INFORMATION DISCLOSURE CITATION</b> <b>APR 28 2005</b> <b>PTO-1449</b> <b>SHEET 1 OF 2</b>	ATTY. DOCKET NO.	SERIAL NO.
	P132-US	10/811,449
	APPLICANT Dunphy, et al.	
	FILING DATE 3/26/04	GROUP Not Yet Assigned

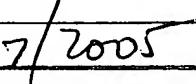
### U.S. PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
	5,939,785	8/17/99	Klonis, et al.			
	5,411,769	8/17/99	Hornbeck			
	6,204,085	3/20/01	Strumpell, et al.			
	2003/0064149	4/3/03	Miller			
	6,259,551	7/10/01	Jacobs			
	5,447,600	9/5/95	Webb			
	6,300,294	10/9/01	Robbins, et al.			
	6,086,726	7/11/00	Renk, et al.			
	6,475,570	11/5/02	Jacobs			
	2004/0100677	5/27/04	Huibers, et al.			
	2004/0125346	7/1/04	Huibers			

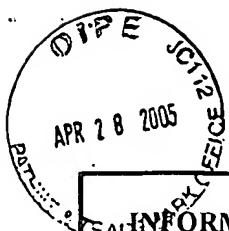
### FOREIGN PATENT DOCUMENTS

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						YES	NO
						<input type="checkbox"/>	<input type="checkbox"/>

### OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

	W. Robert Ashurst, et al., WAFER LEVEL ANTI-STICKTION COATINGS FOR MEMS., Sensors and Actuators A 104 (2003), Pgs 213-221.		
	W. Robert Ashurst et al., VAPOR PHASE ANTI-STICKTION COATINGS FOR MEMS, Pgs 1-6.		
	W. Robert Ashurst, et al., NANOMETER-THIN TITANIA FILMS WITH SAM-LEVEL STICKTION AND SUPERIOR WEAR RESISTANCE FOR RELIABLE MEMS PERFORMANCE, 4 pgs.		
	B.C. Bunker, et al., THE IMPACT OF SOLUTION AGGLOMERATION ON THE DEPOSITION OF SELF-ASSEMBLED MONOLAYERS, 2000 American Chemical Society, Pgs 7742-7751.		
	W. Robert Ashurst, et al., ALKENE BASED MONOLAYER FILMS AS ANTI-STICKTION COATINGS FOR POLYSILICON MEMS, Berkeley Sensor & Actuator Center, 4 pgs.		
	S Imad-Uddin Ahmed, et al., USING SELF ASSEMBLED MONOLAYERS TO REDUCE FRICTION AND WEAR IN POLYSILICON BASED MEMS, 2000, Pgs. 1-18.		
	Uthara Srinivasan, et al., SELF ADDRESSED FLUOROCARBON FILMS FOR ENHANCED STICKTION REDUCTION, 1997 ieee, Pgs. 1399-1402.		
EXAMINER		DATE CONSIDERED	

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#### U.S. PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
Dle	2004/0012838	1/22/04	Huibers	→		
	2004/0100594	5/27/04	Huibers, et al.	→		
	2004/0156090	8/12/04	Patel, et al.	→		
	5,835,256	11/10/98	Huibers	→		
	6,046,840	4/4/00	Huibers	→		
	6,844,959	1/18/05	Huibers, et al.	→		
	6,867,897	3/15/05	Patel, et al.	→		
Dle	5,287,096	2/15/94	Thompson, et al.	→		

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